





When semiconductor chips are bonded to a lead frame (LF) or substrate, the chips are removed from a wafer after dicing by use of a suction jig, known as a "die collet" and then transported. If the suction nozzle is not applied evenly to the semiconductor chips, problems may occur when the chips are removed, or the chips may become flawed. As wafers become thinner and more easily breakable, greater care is required.

Measurement

Product used: Prescale (Ultra Super Low Pressure LLLW, Super Low Pressure LLW)

- Create a plate-shaped dummy wafer that will have a height (thickness) equal to the production wafer after adding 200-µm-thick layer of Prescale film.
- When a suction nozzle needs to be changed, place the dummy wafer on the bonding device, insert Prescale (LLW, LLLW), and then perform the suction operation.
- Check the evenness of the film coloring after suction application and confirm whether the suction nozzle was applied evenly to the wafer.







*Note that the specifications and performance data described in this catalog are subject to change without notice for the purpose of improvement. Since the images provided are used for illustration purposes, they may differ slightly from actual products.

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